

Mark Pallay

List of Publications by Year in descending order

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Version: 2024-02-01

11
papers

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citations

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11
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85
citing authors

#	ARTICLE	IF	CITATIONS
1	Dynamic behavior of an electrostatic MEMS resonator with repulsive actuation. <i>Nonlinear Dynamics</i> , 2017, 89, 1525-1538.	5.2	43
2	A parametric electrostatic resonator using repulsive force. <i>Sensors and Actuators A: Physical</i> , 2018, 277, 134-141.	4.1	26
3	A reliable MEMS switch using electrostatic levitation. <i>Applied Physics Letters</i> , 2018, 113, .	3.3	22
4	Merging parallel-plate and levitation actuators to enable linearity and tunability in electrostatic MEMS. <i>Journal of Applied Physics</i> , 2019, 126, .	2.5	19
5	A Tunable Electrostatic MEMS Pressure Switch. <i>IEEE Transactions on Industrial Electronics</i> , 2020, 67, 9833-9840.	7.9	17
6	Pairing electrostatic levitation with triboelectric transduction for high-performance self-powered MEMS sensors and actuators. <i>Applied Physics Letters</i> , 2019, 115, .	3.3	14
7	Towards a high bias voltage MEMS filter using electrostatic levitation. <i>Mechanical Systems and Signal Processing</i> , 2021, 150, 107250.	8.0	12
8	Parametrically Excited Electrostatic MEMS Cantilever Beam With Flexible Support. <i>Journal of Vibration and Acoustics, Transactions of the ASME</i> , 2017, 139, .	1.6	10
9	Feasibility study of a micro-electro-mechanical-systems threshold-pressure sensor based on parametric resonance: experimental and theoretical investigations. <i>Journal of Micromechanics and Microengineering</i> , 2021, 31, 025002.	2.6	6
10	Threshold Pressure Sensing Using Parametric Resonance in Electrostatic MEMS. , 2019, , .		1
11	A Combined MEMS Threshold Pressure Sensor and Switch. , 2019, , .		1